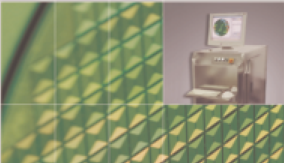
SIRD™ Metrology System

Scanning infrared depolarization tool
for monitoring of process related stress in wafers



- Defect mapping/imaging and screening
- Process quality monitoring
- Process tool verification
- Yield improvement
- <1 min measuring time per wafer possible
- In-line capability

PVA TePla